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APPLICATION NO.		FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/781,945		02/20/2004	Norbertus Josephus Martinus Van Den Nieuwelaar	081468-0308367	9699
909	7590	08/09/2005		EXAM	IINER
PILLSBUR	Y WIN	THROP SHAW	RUTLEDGE, DELLA J		
P.O. BOX 10	500				
MCLEAN, V	VA 22	102	ART UNIT	PAPER NUMBER	
,				2851	

**DATE MAILED: 08/09/2005** 

Please find below and/or attached an Office communication concerning this application or proceeding.

,			
	Application No.	Applicant(s)	
	10/781,945	VAN DEN NIEUWELAAR ET AL.	
Office Action Summary	Examiner	Art Unit	
	D. Rutledge	2851	
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with t	the correspondence address	
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period w Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply within the statutory minimum of thirty (3) will apply and will expire SIX (6) MONTHS cause the application to become ABANI	be timely filed  O) days will be considered timely. From the mailing date of this communication.  DONED (35 U.S.C. § 133).	
Status	•		
Responsive to communication(s) filed on  2a) ☐ This action is <b>FINAL</b> . 2b) ☑ This  3) ☐ Since this application is in condition for allowar closed in accordance with the practice under E	action is non-final. nce except for formal matters	· ·	
Disposition of Claims			
4) ☐ Claim(s) <u>1-30</u> is/are pending in the application. 4a) Of the above claim(s) is/are withdraw 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) <u>1-30</u> is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or	vn from consideration.		
Application Papers			
9) The specification is objected to by the Examiner 10) The drawing(s) filed on is/are: a) access applicant may not request that any objection to the or Replacement drawing sheet(s) including the correction of the order and the correction of the corre	epted or b) objected to by drawing(s) be held in abeyance.	See 37 CFR 1.85(a). s objected to. See 37 CFR 1.121(d).	
Priority under 35 U.S.C. § 119	,		
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:  1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the prior application from the International Bureau * See the attached detailed Office action for a list of	s have been received. s have been received in Appl ity documents have been rec i (PCT Rule 17.2(a)).	ication No eived in this National Stage	
Attachmantal			
Attachment(s)  1) Notice of References Cited (PTO-892)  2) Notice of Draftsperson's Patent Drawing Review (PTO-948)  3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)	Paper No(s)/M	mary (PTO-413) ail Date nal Patent Application (PTO-152)	

U.S. Patent and Trademark Office PTOL-326 (Rev. 1-04)

Paper No(s)/Mail Date 4/05.

6) Other: \_\_\_\_.

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#### **DETAILED ACTION**

## Specification

1. The abstract of the disclosure is objected to because the abstract has two paragraphs and "the abstract should be a brief narrative as a <u>single paragraph</u> of 150 words commencing on a separate sheet." Correction is required. See MPEP § 608.01(b).

## Claim Rejections - 35 USC § 102

2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.
- Claims 1 30 are rejected under 35 U.S.C. 102(e) as being anticipated by Allen,
   Jr. et al.

The reference discloses a predictive method in a semiconductor processing facility. The facility has a track apparatus (see col. 1, lines 5 – 29). As shown in Fig. 2, after a substrate lot is selected for processing the look ahead feature is executed and a simulation process is carried out to predict whether a second process /application will be ready for the substrate lot -

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The simulation would inherently comprise modeling and the modeling would use statistical and empirical data, as well as using the process recipe or schedule in order to make the prediction - claims 3-5, 11-13, 19-21, 26-28

The second process and the first process are not always literally the first and second process, rather the terms can become any process in the computer algorithm or recipe for making the semiconductor device and that would include the exposure apparatus. When exposure is the "first process" the method can be used to determine when the exposure apparatus will be ready to deliver the substrate lot to the developer. When the exposure apparatus is the "second process" the method will predict if the exposure apparatus will be ready for the substrate lot. In predicting whether a process will be ready to receive the substrate lot a time period must be used – claims 6, 14, 22, 29. The methods of resolving the problem of the exposure apparatus or some other process not being to receive or deliver the substrate lot is to use the computer or controller to provide an intentional delay. Other units are notified of the delay. The delay may be provides by placing the substrates in a stocking unit – claims 1, 2, 7 - 10,15 – 18, 23 – 25 and 30.

4. Claims 1 – 30 are rejected under 35 U.S.C. 102 (e) as being anticipated by Fujita (US Pat. No. 6,698,944).

Fujita communicates expected times and predicted times of wafer delivery and receipt between the exposure apparatus 10 and a processing apparatus in the track apparatus of the lithocell 100. The reference teaches that if either apparatus will have a delay the

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apparatus can then decide the next operation in the exposure apparatus or in the processing apparatus based on the time information received; alternatively, either apparatus may decide to resolve the problem in relation to the substrate carriage — claims 1, 10, 18, 24. The substrate carriage may be prevented from delivering or receiving a substrate. By preventing the substrate carriage from sending or receiving a substrate an intentional delay is introduced — claims 2, 6 - 9, 15 - 17, 22, 23, 25, 29, 30. The decision can be made before the exposing or processing operation actually begins. The expected time is based on calculation and the predicted time is based on schedule and statistical data - claims 3 - 5, 11 - 13, 19 - 21, 26 - 28. See summary of the invention and col. 17, line 47 to col. 19, line 67.

### Conclusion

5. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. The reference disclose methods of either introducing intentional delays or of resolving of delays such a using a priority method.

#### Response Data

Any inquiry concerning this communication or earlier communications from the examiner should be directed to D. Rutledge whose telephone number is (571) 272-2127. The examiner can normally be reached on Mon - Thurs, 6:00 AM - 4:30 PM.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Judy Nguyen can be reached on (571) 272-2258. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

D. Rutledge Primary Examiner Art Unit 2851

dr 8/3/05